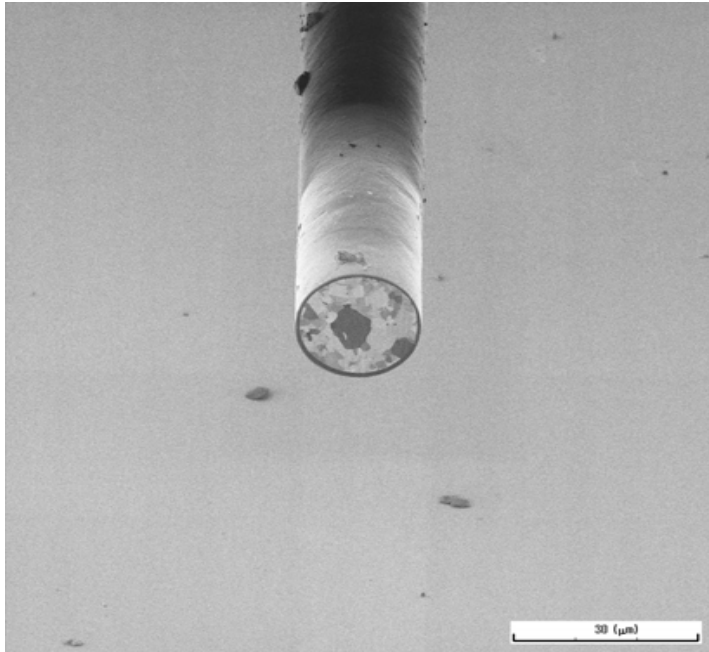


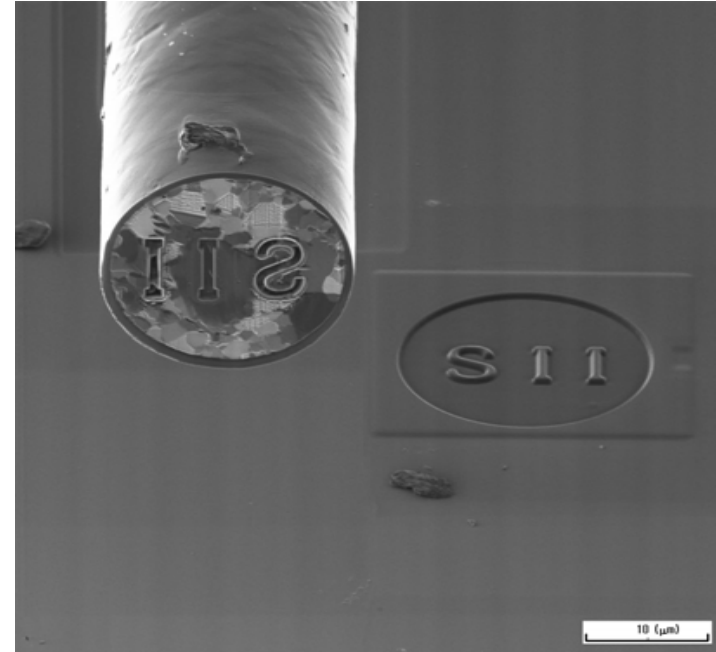
SII NanoTechnology Inc.
FIB Application

Microscopic Processing with FIB

3D Processing Micro-Stamp

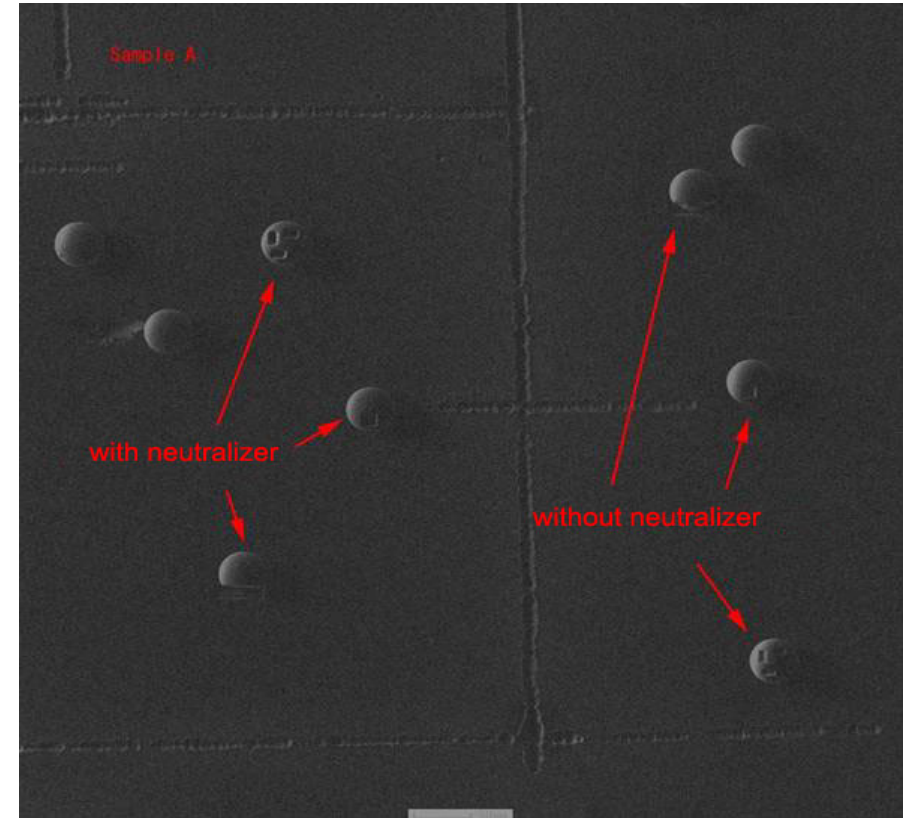
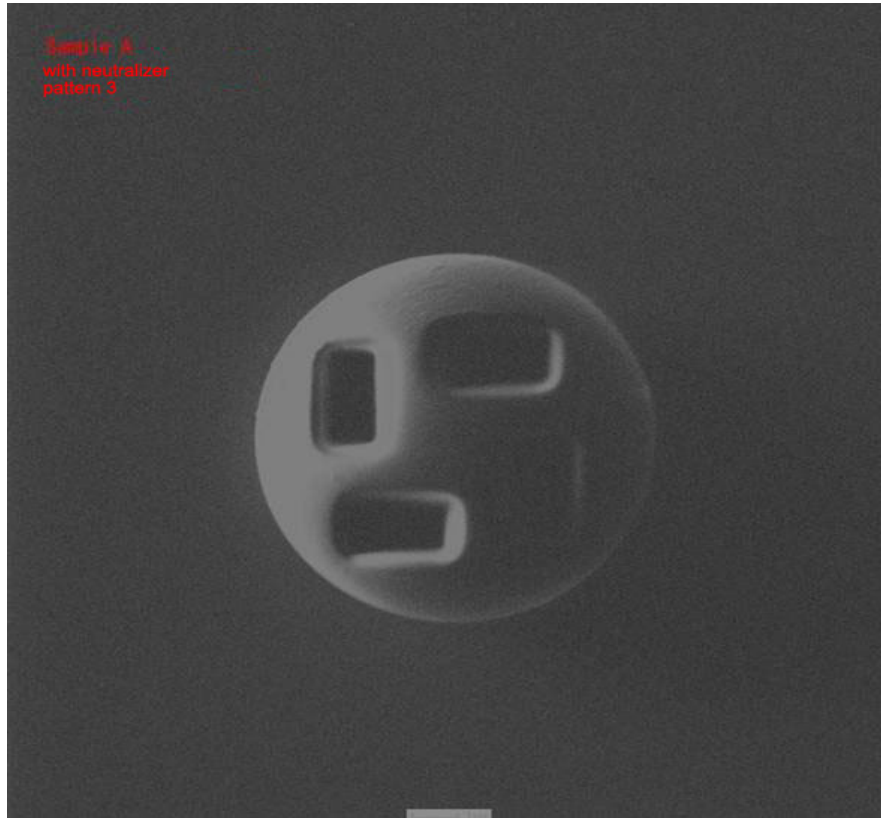


Cross-sectional image of Cu wire observed with Scanning Ion Microscope



FIB processing of Cu wire cross section and Si circuit board

FIB Processing of Minute Particles



Few score micron order to nano order processing is enabled with etching function of FIB. It is now used in wide range of applications as a micromachining tool for its feature of hardly applying heat or strain at processing.